

**METHOD AND APPARATUS FOR REMOTELY TESTING
SEMICONDUCTORS**

ABSTRACT

An apparatus is disclosed for remotely monitoring and developing steps in a semiconductor manufacturing process that includes, at least one remote workstation connected via a remote access link to a local workstation, and a test system connected via 5 a link to the local workstation. A method is also disclosed that includes running a semiconductor test system remotely, monitoring the semiconductor test system remotely, and receiving data from the semiconductor test system remotely. Another embodiment includes an apparatus for remotely monitoring and developing steps in a semiconductor manufacturing process. This embodiment includes a plurality of remote workstations 10 each connected via a remote access link to a local workstation, and a test system connected via a link to a local workstation. Security features in this embodiment prevent any one remote workstation from accessing any other remote workstation.

07150.003001.20000809.doc